IN THE CLAIMS

Claims 1-13 (Canceled).

14. (Currently amended) A method, comprising:

positioning a disk, having a hole defined by an inner diameter edge of the disk, over a nest; and

guiding the disk into close proximity of the nest by directing gas into the inner diameter hole of the disk through ~~a~~ an angled gas port aimed toward the inner diameter hole of the disk.

15. (Previously presented) The method of claim 14, wherein positioning further comprises admitting gas into a first port to distribute the gas around a manifold of a pickup head that receives the disk for positioning over the nest.

16. (Original) The method of claim 15, wherein positioning further comprises creating a low gas pressure and a positive gas pressure within the manifold to suspend the disk into close proximity of the manifold.

17. (Previously presented) The method of claim 16, wherein guiding further comprises transferring gas to a second port of the pickup head coupled to a plurality of gas jets directed towards the hole of the disk.

18. (Currently amended) ~~The method of claim 16 wherein creating the low gas pressure and the positive gas pressure produces,~~ A method, comprising:

positioning a disk, having a hole defined by an inner diameter edge of the disk, over a nest, wherein positioning further comprises creating a low gas pressure and a positive gas pressure, producing a Bernoulli effect, within the manifold to suspend the disk into close proximity of the manifold; and

guiding the disk into close proximity of the nest by directing gas into the inner diameter hole of the disk through a gas port aimed toward the inner diameter hole of the

disk.

19. (Original) The method of claim 14, further comprising centering the disk within the nest.

20. (Currently amended) ~~The method of claim 14, further comprising~~ A method, comprising:

positioning a disk, having a hole defined by an inner diameter edge of the disk, over a nest; and

guiding the disk into close proximity of the nest by directing gas into the inner diameter hole of the disk through a gas port aimed toward the inner diameter hole of the disk; and

maintaining the gas at an elevated temperature being above room temperature.

21. (Original) The method of claim 20, wherein the elevated temperature comprises an embossing temperature.

22. (Original) The method of claim 20, further comprises nano-imprinting an embossable film disposed above the disk substrate.

23. (Original) The method of claim 17, wherein transferring gas to the second port further comprises directing gas flow to an inner diameter of the disk.

24. (Previously presented) The method of claim 19, wherein centering further comprises engaging an outer edge of the disk with a plurality of rods coupled to actuators.

Claims 25-33 (Canceled).